What is claimed is:

1. A microelectromechanical system comprising:

substrate means for fabricating microelectromechanical components thereon;

platform means, fabricated on said substrate means, for supporting a desired optical element thereon, said platform means being elevatable in their entirety from said substrate means; and

at least one rotatable lever means, fabricated on said substrate means, for applying force to said platform means to achieve inclination of said platform means in at least a first direction that is the same as a direction in which said lever means are rotatable.

2. The microelectromechanical system of Claim 1 wherein said desired optical element comprises one of an optically reflective surface, a diffraction grating, a lens, and an optical polarizer.

3. The microelectromechanical system of Claim 1 further comprising:

actuation means, fabricated on said substrate means, for rotating said lever means.

4. The microelectromechanical system of Claim 3 wherein said actuation means comprise an electrostatic actuator.

5. The microelectromechanical system of Claim 1 wherein said substrate means comprises a silicon wafer.

6. The microelectromechanical system of Claim 1 wherein said platform means comprises a layer of one of monocrystalline and polycrystalline silicon deposited on said substrate means.

7. The microelectromechanical system of Claim 1 wherein said lever means comprise an A-frame structure.

8. The microelectromechanical system of Claim 1 further comprising:

first compliant means for attaching said lever means to said platform at a first attachment location; and

second compliant means for attaching said platform means to said substrate means at a second attachment location.

9. The system of Claim 8 wherein said first and second compliant means comprise springs.